

II. Listing of Claims

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Previously Presented) A MEMS device, comprising:
a plurality of actuator layers formed over a substrate, including a first layer and a second layer;
a bimorph actuator having a substantially serpentine pattern, wherein the serpentine pattern is a staggered pattern having a plurality of static segments interlaced with a plurality of deformable segments, each of the plurality of static segments having a static segment length and each of the plurality of deformable segments having a deformable segment length, wherein the deformable segment length is substantially different than the static segment length, wherein at least a portion of each of the plurality of static segments is defined from the first layer, and wherein at least a portion of each of the plurality of deformable segments is defined from both of the first and second layers.
2. (Previously Presented) The device of claim 1 wherein the first and second layers are adjacent.
3. (Previously Presented) The device of claim 1 wherein the first and second layers have different coefficients of thermal expansion.
4. (Currently Amended) The device of claim 1 further comprising a payload coupled to the bimorph actuator and movable between first and second orientations in response to exposure of the bimorph actuator to ~~one of thermal energy and~~ electrical energy.
5. (Original) The device of claim 1 wherein at least one of the plurality of deformable segments and the plurality of static segments has a substantially rectilinear pattern.
6. (Original) The device of claim 1 wherein at least one of the plurality of deformable segments and the plurality of static segments has a substantially curvilinear pattern.

Claims 7-9. (Canceled).

10. (Currently Amended) The device of claim [[7]] 1 further comprising a payload coupled to the bimorph actuator and movable between first and second orientations in response to exposure of the bimorph actuator to ~~one of thermal energy and electrical energy~~.

Claims 11-15. (Canceled).

16. (Currently Amended) The device of claim [[13]] 1 further comprising a payload coupled to the bimorph actuator and movable between first and second orientations ~~in response to exposure of the bimorph actuator to one of thermal energy and electrical energy~~ relative to the substrate.

Claims 17 and 18. (Canceled).

19. (Currently Amended) The device of claim [[13]] 1 wherein the actuator has a patterned line width of less than about 50 microns.

20. (Currently Amended) The device of claim [[13]] 1 wherein the actuator has a patterned line width of less than about 1000 nm.